

ABSTRACT

Method, Computer Program Product and Apparatus for Substrate Processing

5 A method of scheduling one or more maintenance actions in at least a part of a substrate processing system is provided. According to an embodiment, the method includes determining a gap in the flow of substrates in a part of the substrate processing system and scheduling one or more maintenance actions to be performed in another part of the substrate processing during a period associated with the gap. An increase of productivity of substrate processing can be
10 achieved through a reduction in downtime in a substrate processing system by appropriate scheduling of maintenance actions.

Fig. 4